



GP 2815

## IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re the Patent Application of )  
 Yukiyasu SUGANO et al. ) Group Art Unit: 2815  
 Serial No. 09/478,812 ) Examiner: E. Lee  
 Filed: January 7, 2000 )  
 For: Process For Producing Thin )  
 Film Semiconductor Device And )  
 Laser Irradiation Apparatus )

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 APR 23 2001  
 TECHNOLOGY CENTER 2800

COMMISSIONER FOR PATENTS  
 Washington, D.C. 20231

Sir:

Transmitted herewith is an amendment in the above-identified application.

No additional fee is required.

The fee has been calculated as shown below

## CLAIMS AS AMENDED

	CLAIMS REMAINING AFTER AMENDMENT		HIGHEST NO. PREVIOUSLY PAID FOR	PRESENT EXTRA	RATE	ADDITIONAL FEE
TOTAL CLAIMS	73	MINUS	74	=0	x \$9 \$18	\$0.00
INDEP. CLAIMS	31	MINUS	31	=0	x\$40 \$80	\$0.00
Fee for Multiple Dependent Claims \$130/\$260						
			TOTAL ADDITIONAL FEE FOR THIS AMEND- MENT		\$0.00	

- If the entry in Column 2 is less than the entry in Column 4,  
     write "0" in Column 5.

\*\* If the "Highest Number Previously Paid For" IN THIS SPACE is less than 20, write "20" in this space.

\*\*\* If the "Highest Number Previously Paid For" IN THIS SPACE is less than 3, write "3" in this space.

- A Letter to the Official Draftsperson is enclosed.
- A Change of Address is enclosed.
- Charge \$\_\_\_\_\_ to Deposit Account No. 18-0013. A duplicate copy of this sheet is enclosed.
- Any prior general authorization to charge an issue fee under 37 C.F.R. 1.18 to Deposit Account No. 18-0013 is hereby revoked. The Commissioner is hereby authorized to charge any additional fees under 37 CFR 1.16 and 1.17 which may be required during the entire pendency of this application, or to credit any overpayment, to Deposit Account No. 18-0013. A duplicate copy of this sheet is enclosed.
- Charge \$\_\_\_\_\_ to Deposit Account No. 18-0013 to cover the Extension fee for response within \_\_\_\_\_ month(s).
- Applicant's undersigned attorney may be reached by telephone in our Washington D.C. Office at

(202) 955-3750.

All correspondence should be directed to our below listed address.

Date:

*April 19, 2001*

Ronald P. Kananen  
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SON-1718



PATENT APPLICATION

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

9/19/01  
APR 19 2001

In the Patent Application of  
Yukiyasu SUGANO et al.

Serial No. 09/478,812

Filed: January 7, 2000

For: Process For Producing Thin  
Film Semiconductor Device And  
Laser Irradiation Apparatus

Group Art Unit: 2815

Examiner: E. Lee

RECEIVED  
PATENT AND TRADEMARK OFFICE  
JAN 23 2001  
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AMENDMENT

Commissioner of Patents  
Washington, DC 20231

Sir:

In response to the non-final Official Action mailed on  
January 19, 2001 (Paper No. 8), please amend the above-  
identified application as follows:

IN THE CLAIMS:

Please cancel claim 64, and amend the claims as shown in  
the Appendix. The claims as amended are provided below.

*Sub B1> A*  
11. (amended) A thin film semiconductor device comprising  
a semiconductor thin film, a gate insulating film accumulated  
on one surface thereof, and a gate electrode accumulated on  
said semiconductor thin film through said gate insulating thin  
film,

wherein said semiconductor thin film is formed by forming